## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLN. OF:

OHTO et al.

FILED:

December 30, 2003

FOR:

ORGANIC INSULATING FILM, MANUFACTURING METHOD THEREOF, SEMICONDUCTOR DEVICE USING SUCH ORGANIC INSULATING FILM AND MANUFACTURING METHOD THEREOF

DOCKET:

NEC NE03P181

MAIL STOP PATENT APPLICATION Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Dear Sir:

In connection with the above-entitled matter, Applicants hereby attach U.S. Patent Office Form PTO-1449, including copies of the references listed therein, which were considered prior to the initial filing. The claims in the present application are believed to be patentably distinguished over these references.

This information disclosure statement is being made pursuant to the duty of disclosure imposed by law and formulated in 37 CFR 1.56(A). No representation is made that the information thus disclosed in fact constitutes prior art or that it is the closest prior art, inasmuch as 37 CFR 1.56(A) relies on a materiality concept which depends on subjectivity.

In the event there are any fee deficiencies or additional fees are payable, please charge them (or credit any overpayment) to our Deposit Account No. 08-1391.

Respectfully submitted,

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## INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional) NEC NE03P181	Application Number			
Applicant(s) OHTO et al.				
Filing Date	Group Art Unit			

	December 30, 2003				0, 2003	Group Art Ont				
				U.S. PATE	NT DOCUMENTS					
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE		NAME	CLASS	SUBCLASS	FILING DATE  IF APPROPRIATE		
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	REF	DOCUMENT NUMBER	DATE	COUNTRY		CLASS			Translation YES NO	
, .		2001-127159	11.05.2001	JAPAN	(w/Abstract)	H01L	21/768		1	
		2002-083870	22.03.2002	JAPAN (w/Abstract)		H01L	21/768		1	
		2002-275631	25.09.2002	JAPAN	(w/Abstract)	C23C	16/42		1	
·		WO 99/41423	19.08.1999	WIPO		C23C	A2		1	
		WO 00/19498 06.04.2000		WIPO		H01L	21/027		1	
			<del></del>	OTHER D	OCUMENTS (Includ	ling Author, Title,	Date, Pertinent Pag	ges, Etc.)		
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EXAMINE	R				DATE CONSIDERED					

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